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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Complete if Known	
Application Number	10/768,558
Filing Date	January-29, 2004
First Named Inventor	Christopher Hamlin
Group Art Unit	2825
Examiner Name	S. Whitmore
Attorney Docket No.	03-2099

Sheet 1 of 1

U.S. PATENT DOCUMENTS

Examiner Initials	Cite No.	U.S. Patent Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Examiner signature	AP	Date considered	8/3/05

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1/29/04

In Place of FORM PTO-1449 (Modified)	Serial No.:
	Applicant: Christopher Hamlin, et al.
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	Filing Date: January 29, 2004
	Group:
	Atty. Docket No.: 03-2099
	EXAMINER NAME: S. Whitmore

Reference Designation

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Examiner Initial

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Examiner: Date Considered: 8/3/05

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